

Substitute Form PTO-1449 (Modified) U.S. Department of Commerce Patent and Trademark Office Attorney's Docket No. 05542-459003

Application No. 09/134,147

DEC 0 6 2002

Ifformation Disclosure Statement by Applicant (Use several sheets if necessary) Applicant Wallace T.Y. Tang

Filing Date August 14, 1998 Group Art Unit 1763

7437 CFR*52.98(b)

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